

VERSION WITH MARKINGS TO SHOW CHANGES MADE

3. (Amended) The apparatus of claim 1 [or 2], characterized in that the control unit determines the activation voltage value and the activation charge values respectively as a function of the piezoelectric element's (10, 20, 30, 40, 50 or 60) normal voltage, normal charge and a correction factor.

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6. (Amended) The apparatus of claim 3, [4 or 5,] characterized in that the control unit (D) determines the correction factor as a function of temperature.

10. (Amended) The method as defined in claim 8 [or 9], characterized in that the activation voltage and the activation charge values respectively, are a function of the piezoelectric element's (10, 20, 30, 40, 50 or 60) normal voltage, the piezoelectric element's (10, 20, 30, 40, 50 or 60) normal charge and a correction factor.

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13. (Amended) The method as defined in claim 10, [11 or 12,] characterized in that the control unit determines the correction factor as a function of temperature.

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15. (Amended) The method as defined in claim 10 [3-14], characterized in that the correction factor is measured as a part of the manufacturing process.

16. (Amended) The method as defined in claim 10 [3-15], characterized in that the correction factor is stored for each cylinder within an EEPROM of the control unit (D).